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Sheet 1 of 1

Form PTO-1449 (REV. 8-83)	-	US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 110157.98		APPLICATION NO. 09/779,686	
INFOR	MATION DISCLOSURE STATEMEN						
	(Use several sheets if necessary)	K 45.	APPLICANT Kenji NISHI				
(			FILING DATE February 9, 2001		GRO 2851	GROUP 2851	
PADEMAUS. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER		DATE	NAMI	<u> </u>	CLASS	SUB CLASS
AM	3,538,828	11-	1970	GENOVESE	: :	,	
AM	4,747,678	5-19	998	SHAFER et al.			
AM	4,748,478	5-19	988	SUWA et al.	-	All and a second	
AM	4,749,867	6-1988		MATSUSHITA et al.			
AM	4,822,975	4,822,975 4-1		TORIGOE -		-	
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AM	5,004,348	4-19	-1991 MAGOME		<u>.</u>		
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AM	5,227,839	7-19	993	3 ALLEN			
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AM	JP A 4-196513 (w/abstract)	7-19	92	JAPAN		_	_
AM	JP A 63-128713	6-19	88	JAPAN			_
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
AM	Buckley et al., "Step and scan: A systems overview of a new lithography tool", SPIE Vol. 1088 Optical/Laser						
	Microlithography II (1989), p. 424-433.						
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EXAMINER Alan Mathews  Date considered 9-18-200:							2
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